

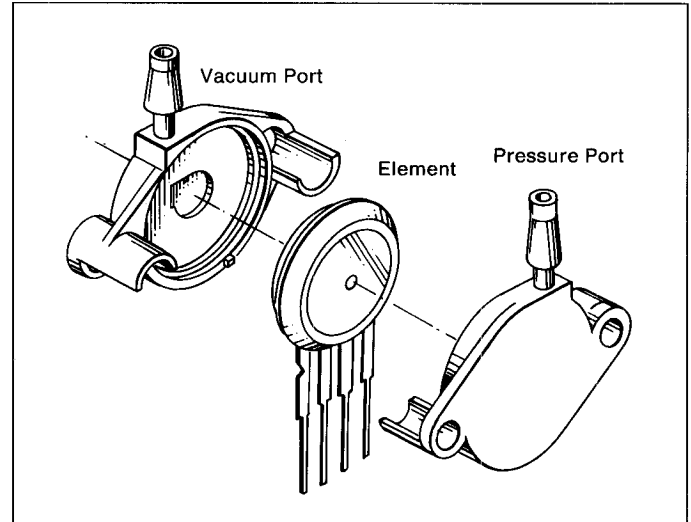
# Sensors

## Pressure Sensors

A unique silicon shear stress sensitive piezoresistive element having an output that is ratiometric to the supply voltage. Devices are available with and without ported housings.

### TWO BASIC ELEMENTS AND THREE PORTED PACKAGES

* Package Suffix	Packages
A	ABSOLUTE Element (zero kPa Reference Vacuum)
AP	ABSOLUTE Element with pressure side ported
D	DIFFERENTIAL Element
DP	DIFFERENTIAL Element with both sides ported
GP	DIFFERENTIAL Element with pressure sides ported
GVP	DIFFERENTIAL Element with vacuum side ported



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### FOUR PRESSURE RANGES

Device	Pressure Range		Full Scale Span Output (mV)	Offset (mV max)	Sensitivity (mV/PSI) Typ	Temperature Effect On Full Scale Span (%/°C) Max
	(PSI)	(mBars)				
MPX10 MPX2010*	0-15	0-100	20 to 50	35	24	-0.2
MPX11			25 to 26	± 1.0	17	+0.01
MPX2011*			30 to 60	35	34	-0.2
MPX12			23 to 27	± 2.0	17	+0.01
			45 to 70	35	38	-0.2
MPX50 MPX2050*	0-7.5	0-500	45 to 90	35	8	-0.2
MPX51			38.5 to 41.5	± 1.0	5.5	+0.01
MPX2051*			30 to 60	35	6	-0.2
MPX52			37.5 to 42.5	± 2.0	5.5	+0.01
			30 to 90	35	8	-0.2
MPX100 MPX2100* MPX2101*	0-15	0-1000	45 to 90	35	4	-0.2
			38.5 to 41.5	± 1.0	2.8	+0.01
			37.5 to 42.5	± 2.0	2.8	+0.01
MPX200 MPX2200* MPX201 MPX2201*	0-30	0-2000	45 to 90	35	2	-0.2
			38.5 to 41.5	± 1.0	1.4	+0.01
			45 to 90	35	2	-0.2
			37.5 to 42.5	± 2.0	1.4	+0.01

\* These devices have internal temperature compensation.